

# EUROPEAN PATENT OFFICE

## Patent Abstracts of Japan

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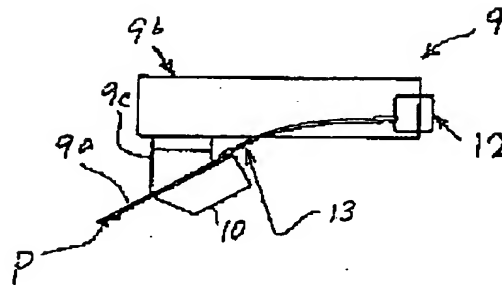
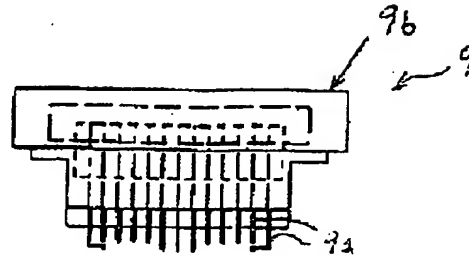
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TITLE : PROBE CARD FOR INSPECTING  
LIQUID CRYSTAL DISPLAY DEVICE



ABSTRACT : PURPOSE: To produce main parts not by manual operations by using means using techniques of ICs and printed wirings, etc.

CONSTITUTION: A silicon oxidized film is formed on a silicon substrate 10 and contact point P patterns to bring probes into contact with ITO electrodes are formed on this oxidized film. Inverted pyramid-shaped cavities arriving at the silicon substrate 10 are formed by anisotropic etching in these pattern parts. Vapor deposited metal layers are formed from the parts formed with these cavities to the positions where the terminals to be connected to external circuits are formed. Hard metallic films are formed by electroplating thereon to form metallic wiring layers of prescribed shapes. The unnecessary exposed silicon parts are removed by an etching means and an assembly formed by connecting the electroplating layers and a connector 12 via the printed wirings formed on the flexible printed circuit board 13 is joined and fixed to a mounting base plate 9b. The probe card is produced by applying the means established as the means for producing semiconductor devices in such a manner.

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